



Cost effective
volume production with

BAK

1101



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Complete range of process components

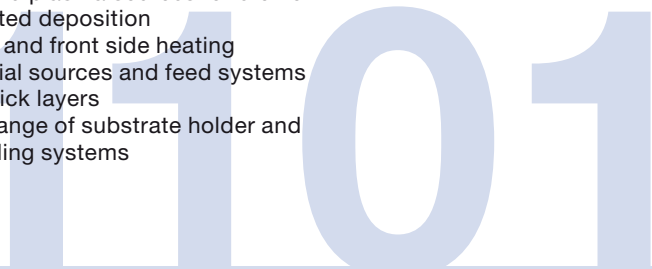
Whatever you process, now or in the future, the flexible system can be configured and reconfigured time after time.

- Up to three EBS500 electron beam guns
- Thermal sources
- Inductively coupled and chimney sources
- Ion and plasma sources for etch or assisted deposition
- Back and front side heating
- Special sources and feed systems for thick layers
- Full range of substrate holder and handling systems

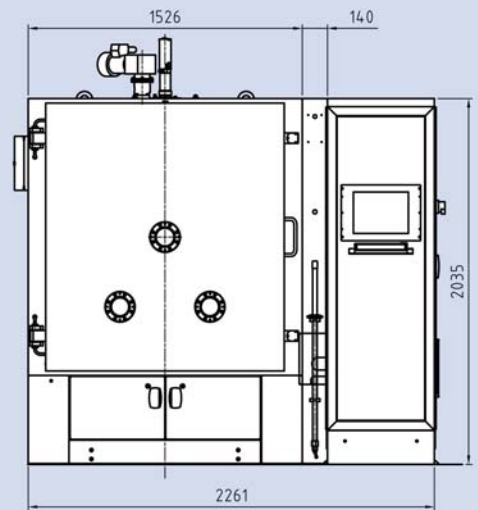
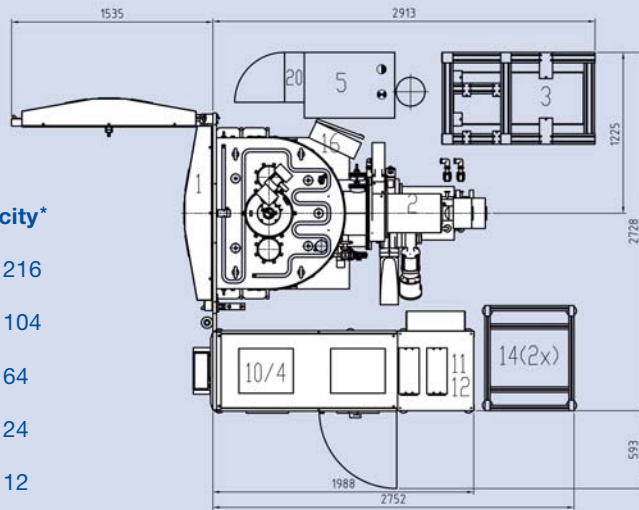
Complete process control

From pump down to system vent, Evatec's user friendly Khan platform ensures all process sequences conform within strict limits for best overall repeatabilities and yields.

- Quartz and Optical Monitoring including broadband
- RGA integration
- Full SECS GEM compatibility



Substrate size		Capacity*
2 inch	●	Up to 216
3 inch	●	Up to 104
4 inch	●	Up to 64
6 inch	●	Up to 24
8 inch	●	Up to 12



*with segmented calotte

